



Ghost Imaging

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Message from the Guest Editors

Beyond being an interesting method of taking pictures of a target object that isn't directly in view, ghost imaging is a very attractive method in the research fields of quantum measurement, quantum information, quantum metrology, and digital imaging processing; which notably improves the performance of optical systems in terms of resolution, reliability, and robustness.

Ghost imaging has been adapted quickly to other research fields. Many interesting applications have recently been proposed in the fields of remote sensing, X-ray imaging, neutron imaging, and so on.

We believe various research fields and technologies may benefit from ghost imaging. We expect, through our efforts, this special issue would be able to publish as many as possible interesting results, ideas, proposals, and discussions about ghost imaging, which could be helpful to the further research and practical applications of ghost imaging itself and to the research and practical applications of other fields.

- Quantum imaging
- Quantum entanglement
- Quantum metrology
- Speckle phenomena
- Signal reconstruction
- Image restoration





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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